Isaku Kanno

List of Publications by Year
in descending order

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159 papers	3,338 citations	172386 29 h-index	155592 55 g-index
162 all docs	162 docs citations	162 times ranked	2734 citing authors

#	Article	IF	Citations
1	Bias-free Photo-electrochemical Water Splitting Driven by Large Photopotential of Epitaxial (Pb,La)TiO₃ Ferroelectric Thin Films. ACS Applied Energy Materials, 2022, 5, 2606-2612.	2.5	2
2	Highly (00l)-textured BiFeO3 thick films integrated on stainless steel foils with an optimized piezoelectric performance. Journal of the European Ceramic Society, 2022, 42, 3454-3462.	2.8	6
3	Limiting current type yttria-stabilized zirconia thin-film oxygen sensor with spiral Ta2O5 gas diffusion layer. Sensors and Actuators B: Chemical, 2021, 327, 128932.	4.0	18
4	Method for Analyzing an Infection Process of Plant-parasitic Nematodes Using a Microfluidic Device. IEEJ Transactions on Sensors and Micromachines, 2021, 141, 141-146.	0.0	0
5	Finger flexion power generators made of piezoelectric lead zirconate titanate thin films on stainless steel foils. Sensors and Actuators A: Physical, 2021, 322, 112617.	2.0	5
6	Transparent piezoelectric thin-film devices: Pb(Zr, Ti)O3 thin films on glass substrates. Sensors and Actuators A: Physical, 2021, 327, 112786.	2.0	16
7	Piezoelectric unimorph microcantilevers for measuring direct and converse piezoelectric coefficients. Journal of Applied Physics, 2021, 130, .	1.1	4
8	Limiting current-type MEMS oxygen gas sensor integrated with micro-hotplate. , 2021, , .		2
9	Fabrication of all-solid-state amorphous thin-film Lithium-ion batteries. , 2021, , .		1
10	In Situ XRD Observation of Crystal Deformation of Piezoelectric (K,Na)NbO₃ Thin Films. ACS Applied Electronic Materials, 2020, 2, 2084-2089.	2.0	9
11	Deposition and performance of all solid-state thin-film lithium-ion batteries composed of amorphous Si/LiPON/VO-LiPO multilayers. Thin Solid Films, 2020, 697, 137840.	0.8	13
12	An evaluation method for direct piezoelectric coefficients of thin films using both-ends-hinge-supported unimoprh beams. Japanese Journal of Applied Physics, 2020, 59, SPPB04.	0.8	1
13	Piezoelectric PZT thin-film transformers with a ringâ€“dot structure. Japanese Journal of Applied Physics, 2020, 59, SPPD09.	0.8	4
14	Ultrahigh temperature platinum microheater encapsulated by reduced-TiO2 barrier layer. Sensors and Actuators A: Physical, 2019, 296, 286-291.	2.0	11
15	Fundamentals of piezoelectric thin films for microelectromechanical systems. , 2019, , 237-255.		0
16	Piezoelectric Pzt Thin Films: Deposition, Evaluation and Their Applications. , 2019, , .		6
17	Crystallographic contributions to piezoelectric properties in PZT thin films. Scientific Reports, 2019, 9, 7309.	1.6	26
18	Structural optimization of piezoelectric thin-film vibration energy harvesters based on electric equivalent circuit model. , 2019, , 161-179.		1

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19	Equivalent circuit model of piezoelectric vibration energy harvesters composed of trapezoidal unimorph cantilevers. Journal of Physics: Conference Series, 2019, 1407, 012079.	0.3	0
20	Influence of Zr/Sn ratio on the Transverse Piezoelectric Coefficient [Inline formula] in Lanthanum-Doped Lead Zirconate Titanate Stannate Thin Films. Integrated Ferroelectrics, 2019, 201, 86-93.	0.3	1
21	A Review on Piezoelectric Energy Harvesting: Materials, Methods, and Circuits. Energy Harvesting and Systems, 2019, 4, 3-39.	1.7	288
22	Piezoelectric MEMS: Ferroelectric thin films for MEMS applications. Japanese Journal of Applied Physics, 2018, 57, 040101.	0.8	72
23	Immediate elimination of injured white matter tissue achieves a rapid axonal growth across the severed spinal cord in adult rats. Neuroscience Research, 2018, 131, 19-29.	1.0	3
24	Numerical designs of piezoelectric thin-film vibration energy harvesters. Japanese Journal of Applied Physics, 2018, 57, 11UD06.	0.8	3
25	Transverse piezoelectric properties of {110}-oriented PLZT thin films. Integrated Ferroelectrics, 2018, 192, 113-120.	0.3	2
26	Airflow energy harvester of piezoelectric thin-film bimorph using self-excited vibration. Sensors and Actuators A: Physical, 2017, 261, 295-301.	2.0	28
27	Piezoelectric vibration energy harvesters with stretched and multistacked organic ferroelectric films. Japanese Journal of Applied Physics, 2017, 56, 04CL04.	0.8	8
28	Electromechanical properties of BaTiO3-xBaSnO3 thin films prepared via combinatorial sputtering. Ceramics International, 2017, 43, 1597-1601.	2.3	13
29	Vibration energy harvester with piezoelectric properties using polyurea thin films. Molecular Crystals and Liquid Crystals, 2017, 653, 188-193.	0.4	6
30	Probing domain switching dynamics in ferroelectric thick films by small field e31,f piezoelectric measurement. Applied Physics Letters, 2017, 111, 022904.	1.5	10
31	Piezoelectric characterization of Pb(Zr,Ti)O₃thin films deposited on metal foil substrates by dip coating. Japanese Journal of Applied Physics, 2017, 56, 10PF08.	0.8	3
32	Piezoelectric Thin-Film Actuators. Hyomen Gijutsu/Journal of the Surface Finishing Society of Japan, 2017, 68, 387-391.	0.1	0
33	Piezoelectric Thin Films for MEMS Applications. , 2017, , 41-67.		0
34	Improved transverse piezoelectric properties in {110}-oriented B-site acceptor doped PLZT (8/65/35) thin films. Integrated Ferroelectrics, 2016, 176, 210-219.	0.3	7
35	Composition dependence of transverse piezoelectric properties of preferentially {110}-oriented (1â^'x) PIN-x PT thin films. Journal of Alloys and Compounds, 2016, 688, 863-867.	2.8	1
36	Precise piezoelectric characterization of Pb(Hf,Ti)O3 thin films deposited by combinatorial sputtering. Thin Solid Films, 2016, 616, 444-448.	0.8	3

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37	Simple millimeter-scale robot using Pb(Zr, Ti) piezoelectric thin film actuator on titanium substrate. Microsystem Technologies, 2016, 22, 1429-1436.	1.2	13
38	Electric Power Generation from Environmental Vibration (Vibration Energy Harvesting). Hyomen Gijutsu/Journal of the Surface Finishing Society of Japan, 2016, 67, 348-352.	0.1	5
39	Fabrication of piezoelectric multilayer thin-film actuators. Microsystem Technologies, 2016, 22, 1275-1283.	1.2	2
40	Fabrication of High-Efficiency Piezoelectric Energy Harvesters of Epitaxial Pb(Zr,Ti)O₃ Thin Films by Laser Lift-off. Energy Harvesting and Systems, 2016, 3, 61-67.	1.7	15
41	Characterization of Cylindrical Type MEMS Gyroscope Using Piezoelectric Thin-film Resonator. The Proceedings of Mechanical Engineering Congress Japan, 2016, 2016, J2230103.	0.0	0
42	Comparison of effective transverse piezoelectric coefficientse_{31,f}of Pb(Zr,Ti)O₃thin films between direct and converse piezoelectric effects. Japanese Journal of Applied Physics, 2015, 54, 10NA04.	0.8	69
43	Piezoelectric MEMS for energy harvesting. Journal of Physics: Conference Series, 2015, 660, 012001.	0.3	31
44	Early characterization method of plant root adaptability to soil environments. , 2015, , .		1
45	Multilayer La-modified PbTiO3 capacitors via RF magnetron sputtering. Journal of Materials Science, 2015, 50, 3631-3637.	1.7	3
46	Compositional dependence of Ba(Zr0.2Ti0.8)O3â€“(Ba0.7Ca0.3)TiO3 piezoelectric thin films prepared by combinatorial sputtering. Thin Solid Films, 2015, 588, 34-38.	0.8	12
47	High-productive fabrication method of flexible piezoelectric substrate. , 2015, , .		2
48	Transverse piezoelectric properties of {100} â€“ Oriented PLZT[x/65/35] thin films. Materials Chemistry and Physics, 2015, 151, 308-311.	2.0	5
49	On-chip force measurement system for investigating plant-root growth. , 2014, , .		2
50	Compositional dependence of Pb(Mg_{1/3},Nb_{2/3})O₃â€“PbTiO₃piezoelectric thin films by combinatorial sputtering. Japanese Journal of Applied Physics, 2014, 53, 09PA06.	0.8	7
51	21am2-A8 Transfer process of piezoelectric thin films onto PDMS substrate by using wet etching. The Proceedings of the Symposium on Micro-Nano Science and Technology, 2014, 2014.6, _21am2-A8-_21am2-A8-.	0.0	0
52	20pm1-E3 Fabrication of millimeter-scale robot with piezoelectric thin film actuator on metal substrate. The Proceedings of the Symposium on Micro-Nano Science and Technology, 2014, 2014.6, _20pm1-E3-_20pm1-E3-.	0.0	0
53	Design of MEMS cylindrical gyroscope integrated with piezoelectric thin film. , 2013, , .		0
54	Modeling of metal-based piezoelectric MEMS energy harvesters. , 2013, , .		0

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55	Colocalization of Quantum Dots by Reactive Molecules Carried by Motor Proteins on Polarized Microtubule Arrays. ACS Nano, 2013, 7, 447-455.	7.3	42
56	Lead-Free Piezoelectric MEMS Energy Harvesters of (K,Na)NbO₃ Thin Films on Stainless Steel Cantilevers. Japanese Journal of Applied Physics, 2013, 52, 09KD13.	0.8	48
57	Precise measurement of the transverse piezoelectric coefficient for thin films on anisotropic substrate. Journal of Applied Physics, 2013, 113, .	1.1	39
58	Dry Etching of Lead-Free (K,Na)NbO$_{3}$ Piezoelectric Films by Ar/C$_{4}$F$_{8}$ Plasma. Japanese Journal of Applied Physics, 2012, 51, 076202.	0.8	4
59	Composition Dependence of Piezoelectric Properties of Pb(Zr,Ti)O₃Films Prepared by Combinatorial Sputtering. Japanese Journal of Applied Physics, 2012, 51, 09LA12.	0.8	19
60	Perfusable multi-scale channels fabricated by integration of nanoimprint lighography (NIL) and UV lithography (UVL). Microelectronic Engineering, 2012, 98, 58-63.	1.1	11
61	Highly polarized single-c-domain single-crystal Pb(Mn,Nb)O₃-PZT thin films. IEEE Transactions on Ultrasonics, Ferroelectrics, and Frequency Control, 2012, 59, 6-13.	1.7	24
62	Thin Film MEMS. , 2012, , 559-596.		1
63	Piezoelectric MEMS for energy harvesting. MRS Bulletin, 2012, 37, 1039-1050.	1.7	286
64	Nano-particle deposition system (NPDS): Low energy solvent-free dry spray process for direct patterning of metals and ceramics at room temperature. International Journal of Precision Engineering and Manufacturing, 2012, 13, 1107-1112.	1.1	40
65	Metal-based piezoelectric microelectromechanical systems scanner composed of Pb(Zr, Ti)O3 thin film on titanium substrate. Microsystem Technologies, 2012, 18, 765-771.	1.2	17
66	A perfusable microfluidic device with on-chip total internal reflection fluorescence microscopy (TIRFM) for in situ and real-time monitoring of live cells. Biomedical Microdevices, 2012, 14, 791-797.	1.4	11
67	Power-generation performance of lead-free (K,Na)NbO3 piezoelectric thin-film energy harvesters. Sensors and Actuators A: Physical, 2012, 179, 132-136.	2.0	118
68	Influence of lithium doping on the structural and electrical characteristics of ZnO thin films. Thin Solid Films, 2012, 520, 5797-5800.	0.8	10
69	Thin-Film Piezoelectric Materials For a Better Energy Harvesting MEMS. Journal of Microelectromechanical Systems, 2012, 21, 451-457.	1.7	68
70	Deposition Of PZT Thin Films With (001), (110),Âand (111) Crystallographic Orientations And TheirÂtransverse Piezoelectric Characteristics. Advanced Materials Letters, 2012, 3, 102-106.	0.3	32
71	Composition Dependence of Piezoelectric Properties of Pb(Zr,Ti)O₃Films Prepared by Combinatorial Sputtering. Japanese Journal of Applied Physics, 2012, 51, 09LA12.	0.8	9
72	OS4-1-1 Piezoelectric energy harvesters of PZT films deposited on stainless steel. The Proceedings of the Symposium on Micro-Nano Science and Technology, 2012, 2012.4, 91-92.	0.0	0

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73	Shear piezoelectric coefficient d<inf>15</inf> of c-axis oriented epitaxial Pb(Zr,Ti)O<inf>3</inf> films. , 2011, , .		0
74	Selective kinesin and dynein immobilizaton and electrical microtubule manipulation for bidirectional microtubule motility. , 2011, , .		0
75	Piezoelectric properties of microfabricated (K,Na)NbO3 thin films. Sensors and Actuators A: Physical, 2011, 171, 223-227.	2.0	28
76	Development of piezoelectric MEMS deformable mirror. Microsystem Technologies, 2011, 17, 931-935.	1.2	5
77	Measuring the force of adhesion between multiple kinesins and a microtubule using the fluid force produced by microfluidic flow. Microfluidics and Nanofluidics, 2011, 11, 519-527.	1.0	3
78	Multilayer Thin-Film Capacitor Fabricated by Radio-Frequency Magnetron Sputtering. Japanese Journal of Applied Physics, 2011, 50, 09NA01.	0.8	9
79	Multilayer thin-film capacitors fabricated by radio-frequency magnetron sputtering. , 2011, , .		0
80	Multilayer Thin-Film Capacitor Fabricated by Radio-Frequency Magnetron Sputtering. Japanese Journal of Applied Physics, 2011, 50, 09NA01.	0.8	2
81	D-2-1 Fabrication of Sub-micrometer Channels for Bio-assay Perfusion Device by Integrating Nanoimprint Lithography and UV Lithography. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2011, 2011, 28-29.	0.0	0
82	High-efficiency piezoelectric energy harvesters of c-axis-oriented epitaxial PZT films transferred onto stainless steel cantilevers. Sensors and Actuators A: Physical, 2010, 163, 428-432.	2.0	140
83	Sol-gel deposition and piezoelectric properties of {110}-oriented Pb(Zr0.52Ti0.48)O3 thin films. Applied Physics Letters, 2010, 96, .	1.5	23
84	Orientation Dependence of Transverse Piezoelectric Properties of Epitaxial BaTiO₃ Films. Japanese Journal of Applied Physics, 2010, 49, 09MA09.	0.8	20
85	Orientation Dependence of Shear Mode Piezoelectric Properties of Epitaxial Pb(Zrx,Ti1-x)O3Thin Films. Japanese Journal of Applied Physics, 2010, 49, 09MA07.	0.8	8
86	Ternary perovskite thin films for energy harvesting MEMS. , 2010, , .		2
87	J0207-2-1 Heterotypic cell positioning using electroosmotic flow and observation of cell-cell interactions. The Proceedings of the JSME Annual Meeting, 2010, 2010.6, 239-240.	0.0	0
88	B-4 Fabrication of optical communication device with piezoelectric micro mirror array. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2010, 2010, 73-74.	0.0	0
89	T1601-1-4 Fabrication of piezoelectric cantilever-shaped actuators with lead-free KNbO_3-NaNbO_3 thin films. The Proceedings of the JSME Annual Meeting, 2010, 2010.8, 193-194.	0.0	0
90	J0207-1-6 Bi-directional transport of motor protein by electrophoresis. The Proceedings of the JSME Annual Meeting, 2010, 2010.6, 135-136.	0.0	0

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91	Evaluation of Intrinsic Shear Piezoelectric Coefficientd15ofc-Axis Oriented Pb(Zr,Ti)O3Films. Applied Physics Express, 2009, 2, 091402.	1.1	11
92	Development of liquid pumping devices using vibrating microchannel walls. Sensors and Actuators A: Physical, 2009, 152, 211-218.	2.0	49
93	Simple Fabrication of Metal-Based Piezoelectric MEMS by Direct Deposition of $hbox{Pb}(hbox{Zr},) Tj ETQq1 1 0.784314 rgBT /Ove Systems, 2009, 18, 610-615.	1.7	40
94	P-MCH-04 Piezoelectric micropumping system using PZT thin films(Micro/Nanomechatronics,Technical) Tj ETQq0 0 0 rgBT /Overlock 10 Micromechatronics for Information and Precision Equipment IIP/ISPS Joint MIPE, 2009, 2009, 387-388.	0.0	0
95	M5-3 Fabrication of PZT thin-film actuator by surface-machining process (M5 Actuator and Physical) Tj ETQq1 1 0.784314 rgBT /Overl	0.0	0
96	MCH-01 DEVELOPMENT OF A NOVEL METHOD FOR STRETCHING DNA FIBERS ON MICROBRIDGES FABRICATED BY SINGLE-MASK INCLINED UV LITHOGRAPHY(Micro/Nanomechatronics I,Technical Program of Oral) Tj ETQq0 0 0 rgBT /Overlock 10 Tf 5 Information and Precision Equipment IIP/ISPS Joint MIPE, 2009, 2009, 325-326.	0.0	2
97	T1601-2-1 Development of piezoelectric MEMS deformable mirrors and their application for adaptive optics. The Proceedings of the JSME Annual Meeting, 2009, 2009.8, 245-246.	0.0	0
98	T1601-1-3 Development of piezoelectric MEMS deformable mirrors and their application for adaptive optics. The Proceedings of the JSME Annual Meeting, 2009, 2009.8, 237-238.	0.0	0
99	Fabrication and transverse piezoelectric characteristics of PZT thick-film actuators on alumina substrates. Sensors and Actuators A: Physical, 2008, 148, 134-137.	2.0	34
100	High-density piezoelectric actuator array for MEMS deformable mirrors composed of PZT thin films. , 2008, , .		1
101	Piezoelectric Properties of (K,Na)NbO₃Films Deposited by RF Magnetron Sputtering. Applied Physics Express, 2008, 1, 011501.	1.1	111
102	Modal Analysis for Externally Driven Micropump and Additional Mass Effect of Water. Japanese Journal of Applied Physics, 2008, 47, 5226-5230.	0.8	3
103	Crystalline Structure of Highly Piezoelectric (K,Na)NbO₃ Films Deposited by RF Magnetron Sputtering. Japanese Journal of Applied Physics, 2008, 47, 8909.	0.8	28
104	Ferroelectric properties of Pb(Mn1/3Nb2/3)O3â^'Pb(Zr,Ti)O3 thin films epitaxially grown on (001)MgO substrates. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2008, 26, 985-990.	0.9	26
105	2107 High-resolution Piezoelectric Deformable Mirror for Adaptive Optics. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2008, 2008, 228-231.	0.0	0
106	309 High-density piezoelectric MEMS deformable mirror for adaptive optics. The Proceedings of the JSME Annual Meeting, 2008, 2008.8, 17-18.	0.0	0
107	Genetic Extended-Fiber Network (GEN) Stretched Over Microbridges Fabricated by Single-Mask Inclined UV Lithography. , 2007, , .		1
108	Piezoelectric Properties of Epitaxial NaNbO₃ Thin Films Deposited on (001)SrRuO₃/Pt/MgO Substrates. Japanese Journal of Applied Physics, 2007, 46, 6960.	0.8	41

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109	Piezoelectric properties of (K,Na)NbO₃ thin films deposited on (001)SrRuO₃/Pt/MgO substrates. IEEE Transactions on Ultrasonics, Ferroelectrics, and Frequency Control, 2007, 54, 2562-2556.	1.7	42
110	Piezoelectric properties of (K, Na)NbO<inf>3</inf> thin films deposited on (001)SrRuO<inf>3</inf>/Pt/MgO substrates. Applications of Ferroelectrics, IEEE International Symposium on, 2007, , .	0.0	4
111	High Throughput Cell Electroporation Array Fabricated by Single-Mask Inclined UV Lithography Exposure and Oxygen Plasma Etching. , 2007, , .		9
112	Fabrication of single crystal PZT thin films on glass substrates. Vacuum, 2007, 81, 571-578.	1.6	17
113	Development of Deformable Mirror Composed of Piezoelectric Thin Films for Adaptive Optics. IEEE Journal of Selected Topics in Quantum Electronics, 2007, 13, 155-161.	1.9	73
114	Piezoelectric unimorph miroactuators with X-shaped structure composed of PZT thin films. Microsystem Technologies, 2007, 13, 825-829.	1.2	4
115	Micro cell encapsulation and its hydrogel-beads production using microfluidic device. Microsystem Technologies, 2007, 13, 951-958.	1.2	78
116	Development of a micro biochip integrated traveling wave micropumps and surface plasmon resonance imaging sensors. Microsystem Technologies, 2007, 13, 1391-1396.	1.2	19
117	MEMS Deformable Mirrors for Adaptive Optics Actuated by Piezoelectric PZT Films. IEEJ Transactions on Sensors and Micromachines, 2007, 127, 518-523.	0.0	0
118	3304 Designing piezoelectric deformable mirror by using FEM simulation. The Proceedings of the JSME Annual Meeting, 2007, 2007.7, 295-296.	0.0	0
119	Concepts for a new class of all-polymer micropumps. Lab on A Chip, 2006, 6, 1147.	3.1	98
120	Characterization of Pb(Zr,Ti)O3 thin films deposited on stainless steel substrates by RF-magnetron sputtering for MEMS applications. Sensors and Actuators A: Physical, 2006, 125, 382-386.	2.0	53
121	Electric Field-Induced Strain of PbZrO3Films. Japanese Journal of Applied Physics, 2006, 45, 7258-7261.	0.8	5
122	Structure and Electromechanical Properties of Quenched PMN-PT Single Crystal Thin Films. Advances in Science and Technology, 2006, 45, 1212-1217.	0.2	9
123	Growth and structure of heteroepitaxial lead titanate thin films constrained by miscut strontium titanate substrates. Journal of Materials Research, 2006, 21, 1261-1268.	1.2	5
124	5517 Deformable MEMS mirror using piezoelectric thin film for adaptive optics. The Proceedings of the JSME Annual Meeting, 2006, 2006.7, 319-320.	0.0	0
125	5518 Piezoelectric RF-MEMS switches using X type connectors. The Proceedings of the JSME Annual Meeting, 2006, 2006.7, 321-322.	0.0	0
126	5504 Single-MASK Inclined UV Lithography for Cell Analysis on a Microchip. The Proceedings of the JSME Annual Meeting, 2006, 2006.7, 293-294.	0.0	0

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127	Development of Piezoelectric RF-MEMS Switch Driven by Low Operating Voltage. , 2005, , 2033.		0
128	Characteristics of Liquids Mixing and Mass Transfer in Passivemixer for .MU.TAS. 880-02 Nihon Kikai Gakkai RonbunshÅ« Transactions of the Japan Society of Mechanical Engineers Series B B-hen, 2005, 71, 111-116.	0.2	0
129	Development of Atomization Method in Microchannel and Its Basic Characteristics. 880-02 Nihon Kikai Gakkai RonbunshÅ« Transactions of the Japan Society of Mechanical Engineers Series B B-hen, 2005, 71, 2007-2012.	0.2	3
130	Intrinsic crystalline structure of epitaxial Pb(Zr,Ti)O3 thin films. Journal of Applied Physics, 2005, 97, 074101.	1.1	14
131	Characterization of Transverse Piezoelectric Properties ofc-Axis Oriented PbTiO3Thin Films. Ferroelectrics, 2005, 327, 91-95.	0.3	1
132	2407 Measurement of mechanical properties of a single myocyte using MEMS technique. The Proceedings of the JSME Annual Meeting, 2005, 2005.7, 127-128.	0.0	0
133	1117 Measurement of electrophysiological properties of a single cell using MEMS device. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2005, 2005, 86-87.	0.0	0
134	2506 Development of measuring system for contraction characteristics of a single cardiac myocyte. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2005, 2005, 345-346.	0.0	0
135	914 Transfer method of PZT epitaxial thin films onto glass substrates and evaluation of their dielectric properties. The Proceedings of Conference of Kansai Branch, 2005, 2005.80, _9-27_-_9-28_.	0.0	0
136	2402 Deformable MEMS mirror using PZT thin film for adaptive optics. The Proceedings of the JSME Annual Meeting, 2005, 2005.7, 117-118.	0.0	0
137	2404 Development of fixed-fixed beam type RF-MEMS switches using the piezoelectric thin film. The Proceedings of the JSME Annual Meeting, 2005, 2005.7, 121-122.	0.0	0
138	1119 Development of micro atomizer and its computer aided design. The Proceedings of the Conference on Information Intelligence and Precision Equipment IIP, 2005, 2005, 90-92.	0.0	0
139	Pulsed Laser Deposition of High-Quality (K,Na)NbO3Thin Films on SrTiO3Substrate Using High-Density Ceramic Targets. Japanese Journal of Applied Physics, 2004, 43, 6627-6631.	0.8	103
140	Thermodynamic study ofc-axis-oriented epitaxialPb(Zr,Ti)O3thin films. Physical Review B, 2004, 69, .	1.1	52
141	Optimization of droplet generating method in a microchannel based on instability theory. The Proceedings of the JSME Annual Meeting, 2004, 2004.2, 69-70.	0.0	0
142	Micro liquid mixing using pulsating flow at extremely low Reynolds numbers. The Proceedings of the JSME Annual Meeting, 2004, 2004.2, 67-68.	0.0	1
143	Measurement of electrical and mechanical properties of a living cardiac myocyte using MEMS device. The Proceedings of the JSME Annual Meeting, 2004, 2004.5, 341-342.	0.0	0
144	Development of Thin Film Valveless Micropump Driven by Traveling Wave. The Proceedings of the JSME Annual Meeting, 2004, 2004.7, 357-358.	0.0	0

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145	Measurement of transverse piezoelectric properties of PZT thin films. Sensors and Actuators A: Physical, 2003, 107, 68-74.	2.0	209
146	Crystallographic characterization of epitaxial Pb(Zr,Ti)O3 films with different Zr/Ti ratio grown by radio-frequency-magnetron sputtering. Journal of Applied Physics, 2003, 93, 4091-4096.	1.1	93
147	A passive micromixer based on instability theory of interfacial wave growth. The Proceedings of the Bioengineering Conference Annual Meeting of BED/JSME, 2003, 2003.15, 231-232.	0.0	0
148	Fabrication of Micro Actuator using piezoelectric thin films. The Proceedings of the JSME Annual Meeting, 2003, 2003.7, 225-226.	0.0	0
149	Computer aided design of passive mixer for Î¼TAS. The Proceedings of the JSME Annual Meeting, 2003, 2003.5, 325-326.	0.0	0
150	Structural investigation ofPby(Zr0.57Ti0.43)2â^'yO3films deposited on Pt(001)/MgO(001) substrates by rf sputtering. Physical Review B, 2002, 66, .	1.1	11
151	Characterization and aging response of the d31 piezoelectric coefficient of lead zirconate titanate thin films. Journal of Applied Physics, 1999, 85, 6711-6716.	1.1	121
152	Basic sputtering process and ferroelectric properties of singleâ€“domain singleâ€“crystal thin films of PbTiO3. Integrated Ferroelectrics, 1998, 21, 451-460.	0.3	9
153	Preparation of c-Axis OrientedPb(Zr,Ti)O3Thin Films by RF-Magnetron Sputtering and their Dielectric and Piezoelectric Properties. Japanese Journal of Applied Physics, 1997, 36, 6065-6068.	0.8	26
154	High-energy ion beam analysis of ferroelectric thin films. Applied Surface Science, 1997, 117-118, 453-458.	3.1	1
155	Antiferroelectric PbZrO3 thin films prepared by multiâ€ionâ€beam sputtering. Applied Physics Letters, 1995, 66, 145-147.	1.5	62
156	Preparation of Pb-Based Ferroelectric Thin Films at Room Temperature Using Excimer-Laser-Assisted Multi-Ion-Beam Sputtering. Japanese Journal of Applied Physics, 1995, 34, 5211-5215.	0.8	8
157	Characterization ofPb(Zr,Ti)O3Thin Films Prepared by Multi-Ion-Beam Sputtering. Japanese Journal of Applied Physics, 1994, 33, 574-577.	0.8	18
158	Low-Temperature Preparation of Pb(Zr, Ti)O3Thin Films on (Pb, La)TiO3Buffer Layer by Multi-Ion-Beam Sputtering. Japanese Journal of Applied Physics, 1993, 32, 4057-4060.	0.8	71
159	Ferroelectric PbTiO3Thin Films Prepared by Multi-Ion-Beam Sputter and Ion-Assisted Deposition. Japanese Journal of Applied Physics, 1993, 32, L950-L953.	0.8	13